## IN THE SPECIFICATION

## CLEAN COPY

On page 15, please replace the paragraph starting at line 1 with the following clean copy:

Referring now to Figure 3, surface 11, under inspection by an enhanced optical inspection system 20 in accordance with a preferred embodiment of the present invention is depicted. A partially reflective surface 26 is incorporated within optical inspection system 20 producing an optical resonant cavity between partially reflective surface 26 and surface 11 under inspection. The resonance of the cavity is inherently highly non-linear and therefore it is possible to adjust the length of the cavity by varying the position of the partially reflective surface 26 to enhance a filtering effect. The filtering effect filters a reflected field from the surface, based strictly on the height of the surface.

On page 15, please replace the paragraph starting at line 14 with the following clean copy:

Enhanced optical inspection system 20 includes a detector 27, which is depicted as a CCD array, although other suitable optical

detectors may be used. A lens gathers reflected wavefronts 24A-24C from surface 11 and images the resolution cell 23 on surface 11 on CCD pixel 22 which averages the light reflected from resolution aperture 23. Reflected wavefront 24A represents the entire range of reflections from resolution aperture 23, while reflected wavefront 24B depicts a reflection from a roughness area and wavefront 24C depicts a reflection from defect 15. Note that in contrast to the illustration in Figure 1, reflection 24C from defect 15 does not overlap reflection 24B from the roughness area and can therefore be more easily resolved by detector 27. The multiple reflections set up in the resonant cavity formed by partially reflective surface 26 and surface 11 are highly sensitive to angle, and therefore serve to separate reflections from surface features displaced from each other. Due to the small angular spectrum accepted by the resonant cavity, surface feature reflections will sum in image pixel 22 in a non-coherent manner, causing any interferences to be uncorrelated, significantly decreasing optical noise from surface 11.

On page 17, please replace the paragraph starting at line 5 with the following clean ccpy:

Due to the filtering effect and reduction in the field coupling between surface features, defect 15 can be detected as having a height exceeding acceptance threshold 16, by the techniques of the present invention. Thus, enhanced optical inspection system 20 can achieve results similar to a near-field inspection system, without placing a probe within the near-field region, by filtering out all of acceptable height variations.

On page 20, please replace the paragraph starting at line 1 with the following clean copy:

Enferring now to Figure 6, details of enhanced optical inspection system 20 are depicted. Illumination subsystem 31 produces a beam 36 that is directed at surface under inspection 11 through partially reflective surface 26A. Partially reflective surface 26A produces a Fabry-Perot optical resonant cavity with surface under inspection 11. At the distance at which partially reflective surface 26A and surface under inspection 11 form the optimal Fabry-Perot cavity, the sensitivity is greatest, due to the resonance condition of the Fabry-Perot cavity. Detection subsystem 33 provides detection of the reflected beam, permitting measurement of surface height variations. The presence of the partially reflective surface 26A increases the sensitivity of the

interferometer around the resonant distance of the Fabry-Perot cavity formed between the partially reflective surface 26A and surface under inspection 11.

It is not believed that this letter requires any fees, but if there are any fees incurred by this communication, please deduct them from our Deposit Account NO. 23-0830.

F.espectfully submitted,

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